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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

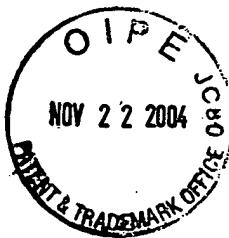
PATENT
5298-04100/PM00012

In re Applicant:
Qiao et al.

Serial No. 09/661,666
Filed: September 14, 2000

Patent No. 6,803,318
Issued: October 12, 2004

For: **METHOD OF FORMING SELF
ALIGNED CONTACTS**



Atty. Docket No. 5298-04100

Group Art Unit: 2813

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313, on the date indicated below:

11/16/2004
Date

Kevin L. Daffer

TRANSMITTAL LETTER

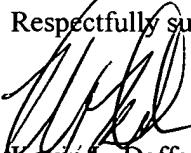
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313

Dear Sir:

Transmitted herewith for filing in the captioned case are the following:

- (1) Form PTO-1050, **submitted in duplicate**. Errors which occur at important points in the captioned patent or which may otherwise affect the understanding or interpretation of the patent are thereon corrected.
- (2) A return postcard to acknowledge receipt of these materials. Please stamp and return this postcard to the undersigned.

All of the errors shown in PTO-1050 are due to Patent Office oversights. A Certificate of Correction is requested under 35 U.S.C. § 254. Applicants believe that no fees are required, however, should any fees be required, please deduct them from deposit account number 50-3268/5298-04100.

Respectfully submitted,

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Date: November 16, 2004

CERTIFICATE OF CORRECTIONPATENT NO. 6,803,318 

DATED: October 12, 2004

INVENTOR(S): Qiao et al.

It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

In the Claims:**Claim 1, col. 21, lines 57-58**

Please delete "chemistries etch are" and substitute therefor "chemistries are--.

Claim 1, col. 21, line 59

Please delete "material silicon" and substitute therefor --material:silicon--.

Claim 8, col. 22, line 27

Please delete "he second" and substitute therefor --the second--.

Claim 16, col. 22, line 56

Please delete "step or" and substitute therefor --step of--.

MAILING ADDRESS OF SENDER:

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PATENT NO. 6,803,318

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UNITED STATES PATENT AND TRADEMARK OFFICE

CERTIFICATE OF CORRECTION

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DATED: October 12, 2004

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